

50103-4721

1 of 3

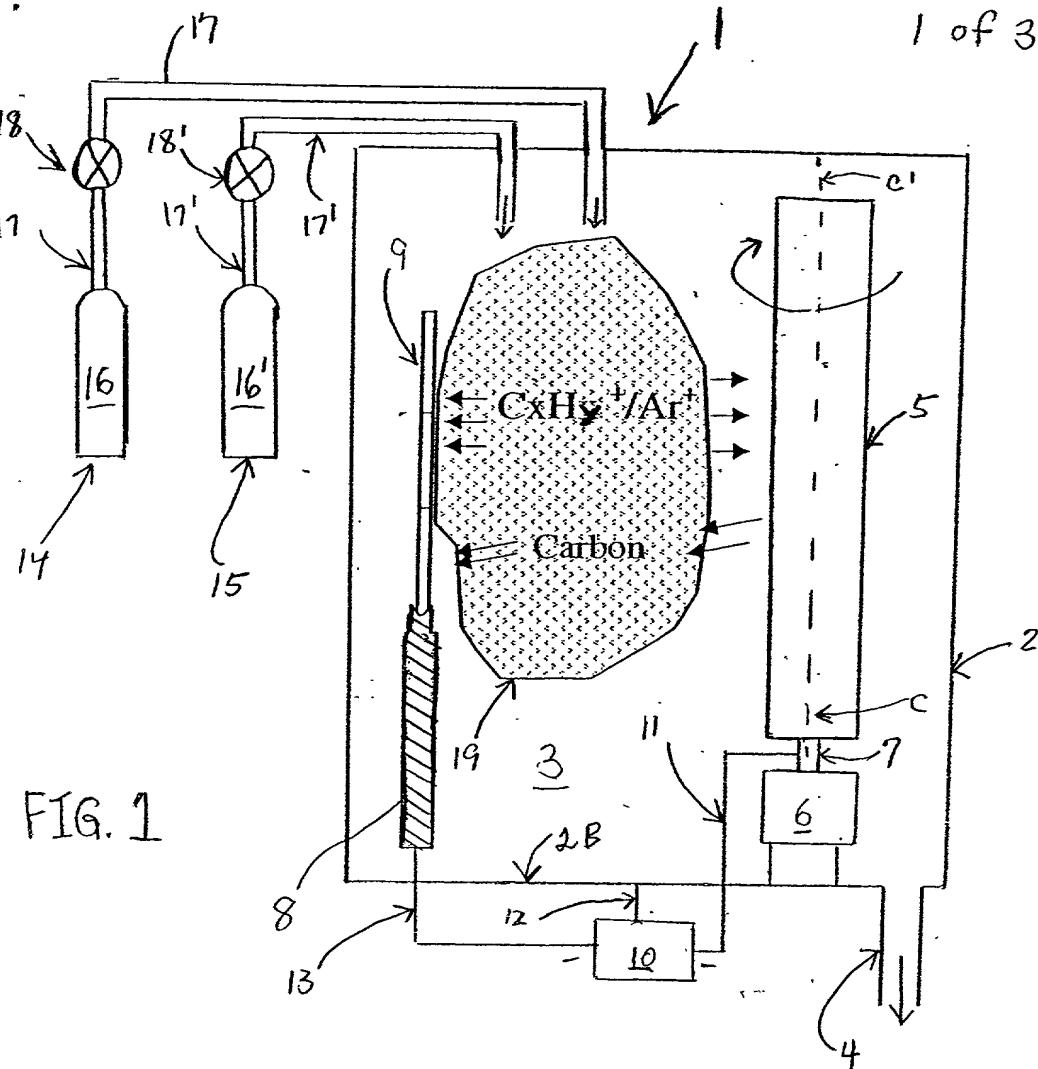


FIG. 1

Percentage Deposited Carbon from C₂H₂ vs C₂H₂ Flow
(Ar flow=146sccm, Pressure ~2.7mTorr)

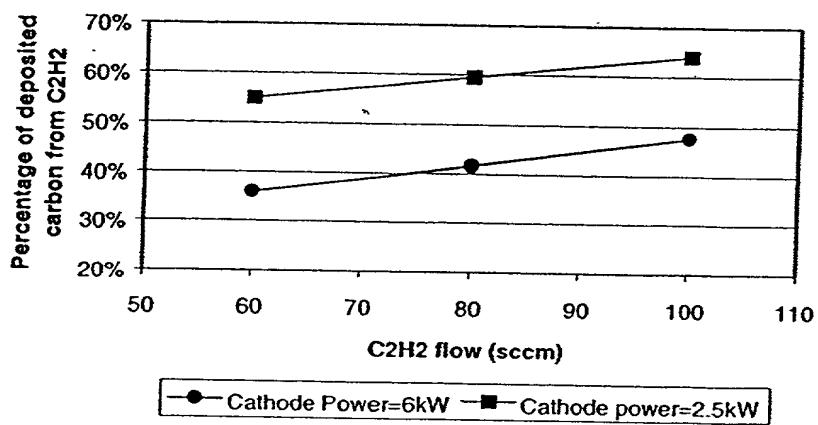


FIG. 2

50103-421

2 of 3

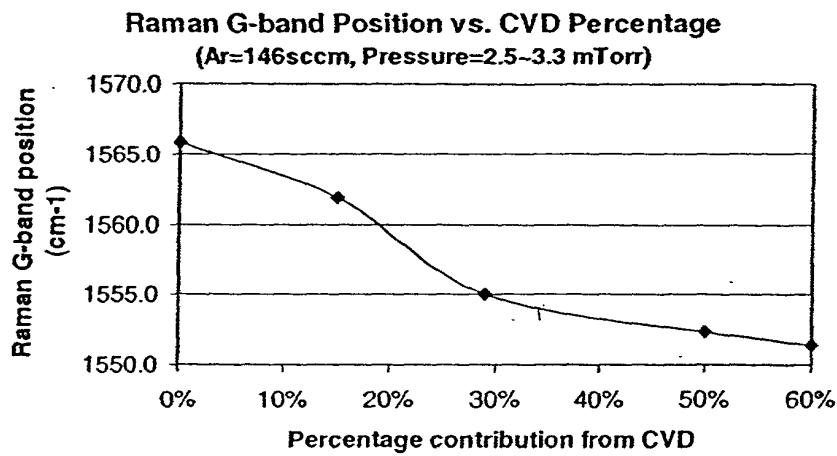


FIG. 3

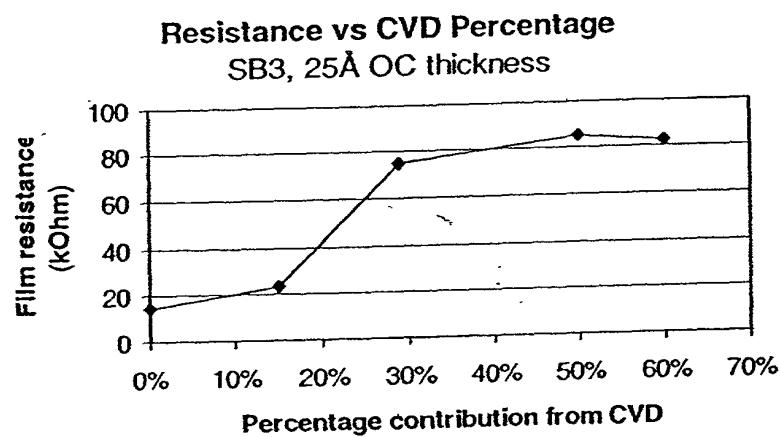


FIG. 4

50103=421

3 of 3

Surface Mark vs C₂H₂ Contribution (F104026)

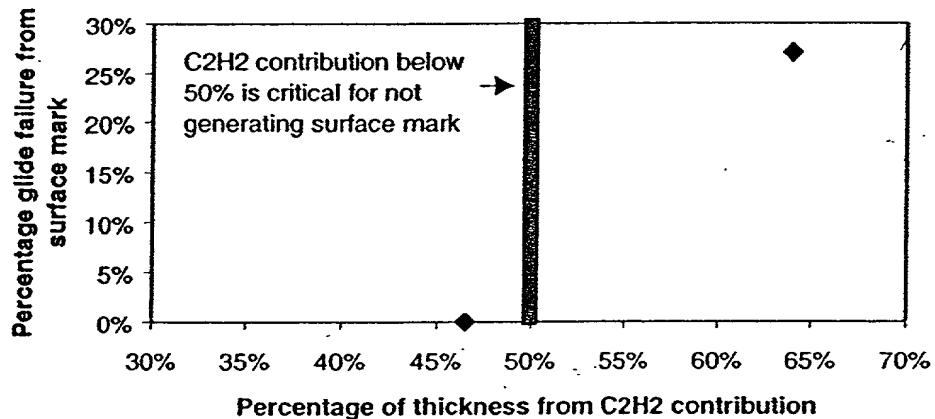


FIG. 5

CoOx Comparison of CVD-assisted Carbon and Sputter Carbon
(After 4 days 80C/80%RH stress)

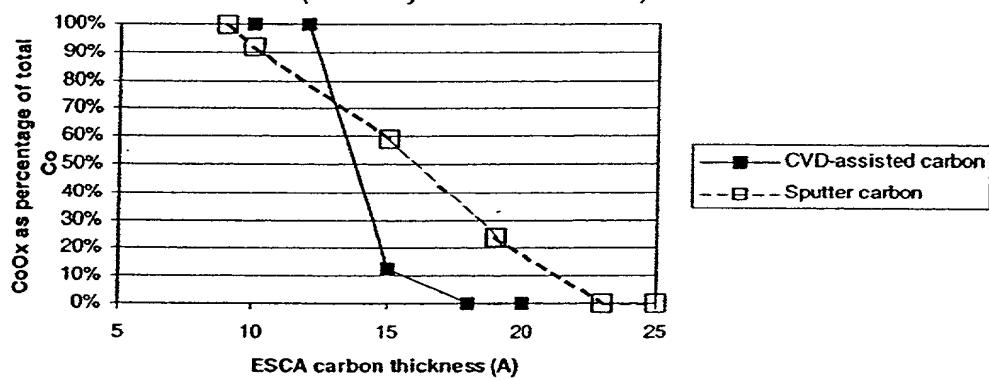


FIG. 6